EUROPEAN CURRICULUM VITAE FORMAT

PERSONAL INFORMATION

Name	**CARMEN GHERASIM**
E-mail	**gherasim.carmen@icmpp.ro**
Nationality	Romanian
Date of birth	15.02.1974

WORK EXPERIENCE

01.09.2017- present
asisstant researcher at **"Petru Poni"**
Institute of Macromolecular Chemistry
01.06.2010-31.03.2013
Technical University "Ghe. ASachi", Iasi
post-doc researcher
Nanomaterials synthesis and characterization by scanning electron microscopy
01.11.2004-31.05.2010
National Insitute for R&D for Technical Physics, Iasi
Scientific researcher
Prepartion and characterization of nanowires arrays; preparation and characterization of magnetic micro and nanosized particles;Electrochemical deposition; Morphological characterization of nanomaterials by SEM, EDS and FIB (micro- and nanoimprinting activities; nanoindentation in ceramic, metallic, polymeric membranes of micrometer thicness to produce nanopillars or nanowire array structures; ionic treatments for nanoclusters growth in amorphous matrices; ion beam corrosion for the preparation of geometrical structures specific for microsensors, microactuators, spin injection systems, etc).
09.1999- 09.2001
Economical Highschool Iaşi
Teacher
Teache of Physics
09.1998–09.1999
Holboca Highschool Iaşi
Teacher
Teacher o Physics

EDUCATION AND TRAINING

01.11.2004-31.01.2009
"Al.I. Cuza" University,Faculty of Physics, Iasi
Doctorate
Doctor's degree
10.1997 – 03.1999

	"Al.I. Cuza" University,Faculty of Physics, Iasi
	Master degree, Physics of Thin Films
	10.1992 – 06. 1997
	"Al.I. Cuza" University,Faculty of Physics, Iasi
	Graduated
PERSONAL SKILLS AND COMPETENCES *Acquired in the course of life and career but not necessarily covered by formal certificates and diplomas*.	
MOTHER TONGUE	**ROAMNIAN**
OTHER LANGUAGES	
	ENGLISH
• Reading skills	VERY GOOD
• Writing skills	VERY GOOD
• Verbal skills	Very good
	FRENCH
Reading skills	Very good
Writing skills	Very good
Verbal skills	Very good
TECHNICAL SKILLS AND COMPETENCES *With computers, specific kinds of equipment, machinery, etc.*	Training for Electron Microscop JEOL JSM 6390A – EDAX, Electron beam lithography system XENOS XP G2; Microtrac Nanotrac 250 Particle Size Analyser; FE-SEM/FIB Carl Zeiss NEON 40EsB; Training for Electron Microscop FE-SEM MIRA II TESCAN; Training for physical analyzes